

Carrying apparatus for carrying a MEMS sensor

Abstract

A carrying apparatus (100) for carrying a microelectromechanical (MEMS) sensor (200) has a carrier platform (110) which is suitable for carrying the MEMS sensor (200), and a coupling structure (120) which has individual, macroscopic springs (130), connected to the carrier platform (110), and which is suitable for being connected to a housing structure (300), wherein the housing structure (300) is suitable for enclosing the carrying apparatus (100) and the MEMS sensor (200) carried by said carrying apparatus.

Figure 4